Electronic Supplementary Material (ESI) for RSC Advances.

Supplementary Data

Goodness of fit (GoF) is a statistical model describing how well the experimental results obtained with a series of observations. GoF value is calculated using equation (1).

$$GoF = \left(\frac{R_{wp}}{R_{exp}}\right)^2 \quad (1)$$

Where GoF is the match value, R_{wp} (weighted profile R-factor) is the simplest difference index and R_{exp} (expected R-factor) is the expected "best R_{wp}" quantity. The Rietveld refinement plot is depicted in Figures S1–S4.

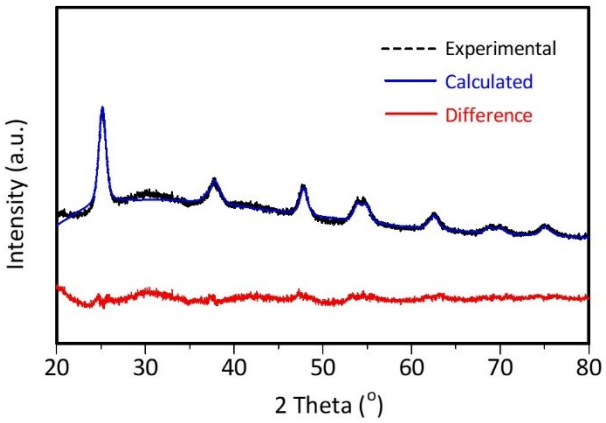

Figure S1. Rietveld refinement of XRD pattern of synthesized TiO_2.

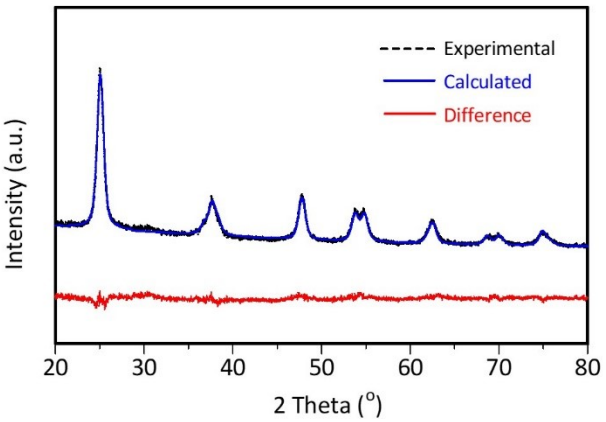

Figure S2. Rietveld refinement of XRD pattern of composite TiO_2-SiO_2 1:0.5.

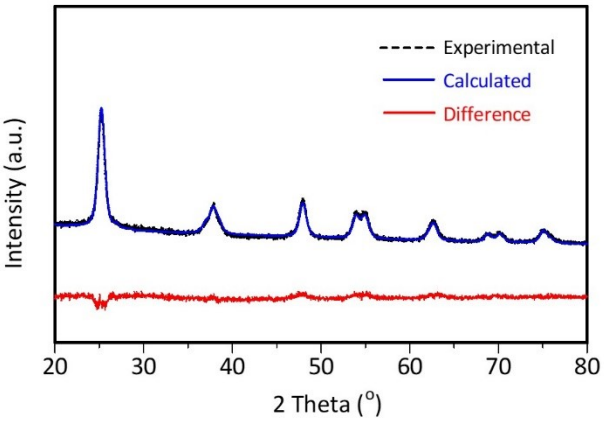

Figure S3. Rietveld refinement of XRD pattern of composite TiO_2-SiO_2 1:1.

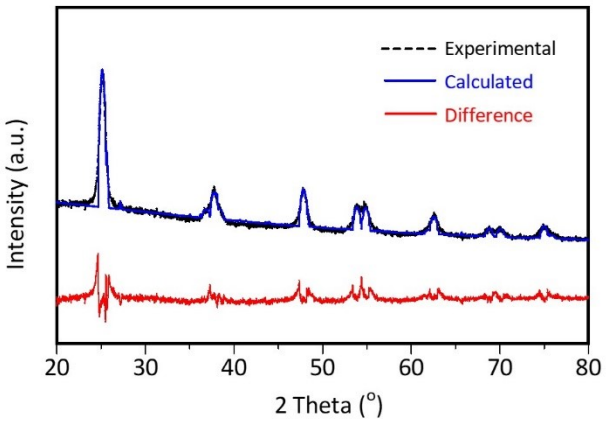

Figure S4. Rietveld refinement of XRD pattern of composite TiO_2-SiO_2 1:2.